



IFW

Docket No.: 055071-0268

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 20277
Xuelong SHI, et al.	:	Confirmation Number: 9791
Application No.: 10/626,864	:	Group Art Unit: 2825
Filed: July 25, 2003	:	Examiner: LEVIN, Naum B.
For: AUTOMATIC OPTICAL PROXIMITY CORRECTION (OPC) RULE GENERATION		

RESPONSE TO RESTRICTION REQUIREMENT

Mail Stop Restriction Requirement
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

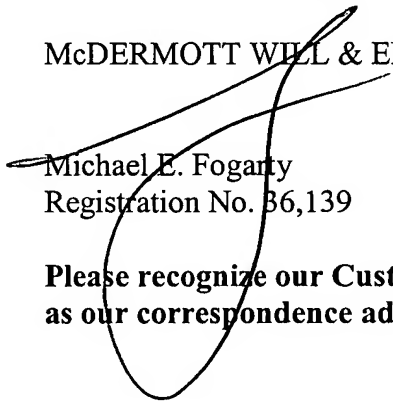
Noting the Office Action of August 18, 2005 wherein restriction has been required, Applicant hereby elects Group I (claims 1-20) for prosecution in the above-identified application.

Furthermore, Applicants respectfully traverse the pending restriction of claim 21 for the following reasons. In the device manufacturing method recited by claim 21, the claim expressly recites that the mask is formed utilizing the method set forth in claim 1. As such, contrary to the conclusion in the restriction requirement, it would not be possible for the device to be manufactured utilizing a mask that is formed by a process other than the process of claim 1. Thus, examination of claims 1-21 in the same application is proper, and does not unduly burden the examiner. Accordingly, it is respectfully requested that the restriction requirement be withdrawn.

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

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Date: September 19, 2005